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MANUFACTURING  
APPARATUS****(57) Abstract:**

**PURPOSE:** To enhance production efficiency by a method wherein the contents of a process corresponding to the kind of article to be processed and a processing apparatus unit and a processing-workpiece transport mechanism are controlled on the basis of the contents of this process.

**CONSTITUTION:** An ID number on a semiconductor wafer 2 is read out by an ID number read-out mechanism. That ID information transmitted to a main control section 33 is transmitted to a recipe control section 35. Recipe information corresponding to this ID information is chosen from recipe information A, B, C stored in recipe storage section 34 by the recipe control section 35. That recipe information is transmitted to the main control section 33 again, and to a carry-in/carry-out mechanism 31 and a process apparatus unit control section 32. Both the carry-in/carry-out mechanism 31 and a process apparatus unit control section 32 control a series of processes on the basis of received recipe information. As a result, manufacture of many kinds of articles in small amounts can be effected easily, and production efficiency is improved.

